Please type a plus sign (+) inside this box ™ +		U.S. Pate	ent and Trademar	PTO/SB/21 (08-00) oved for use through 10/31/02. OMB 0651-0031 tk Office; U.S. DEPARTMENT OF COMMERCE					
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FORM		Filing Date	03						
		First Named Inventor	Jaime Poris						
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be used all correspondence after in.	Examiner Name	Michael A. Lyons							
Total Number Of Pages In This Submission	Attorney Docket No.	NAN042-1D US							
	ENCL OS	URES (check all that	t apply)						
Fee Transmittal Form	Ass	signment Papers	г арріу)	After Allowance Communication to					
Fee Attached	r an Application) awing(s)		Group Appeal Communication to Board of Appeals and Interferences						
Amendment / Reply	ensing-related Papers		Appeal Communication to Group (Appeal Notice, Brief, Reply Brief)						
After Final	tition		Proprietary Information						
Affidavits/declarations	Affidavits/declarations Pe			Status Letter					
Extension of Time Request	l Pre	wer of Attorney, Revocation evious Powers; And Statemed der 37 CFR 3.73(b)		Other Enclosure(s) (please identify below):					
Express Abandonment Request		rminal Disclaimer		* Return Receipt Postcard * Form PTO-1449 (1 page) * Seven References					
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Information Disclosure Statement (2 pages)), Number of CD(s)							
Certified Copy of Priority Document(s)	Remarks								
Response to Missing Parts/									
Incomplete Application Response to Missing Parts under 37 CFR 1.52 or 1.53									
									
SIGNA	TURE OF	APPLICANT, ATTORI	NEY OR AG	ENT					
1	Michael J. Halbert (Reg. No. 40,633)								
Individual Name	Silicon Valley Patent Group LLP								

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2350 Mission College Boulevard, Suite 360

8-03

Santa Clarą, California 95054

Michael J. Halbert

Signature

Date

September 8, 2003

Date



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventors:

Jaime Poris; Claudio L. Rampoldi

Assignee:

Nanometrics Incorporated

Title:

Profiling Method

Serial No.:

10/634,568

Filing Date:

August 4, 2003

Examiner:

Michael A. Lyons

Group Art Unit:

2877

Docket No.:

NAN042-1D US

Confirmation No:

Unknown

Santa Clara, California September 8, 2003

COMMISSIONER FOR PATENTS P.O. BOX 1450 ALEXANDRIA VA 22313-1450

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR §1.97(b)

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, §1.97 and §1.98, the Applicants submit for consideration in the above-identified patent application the document listed on the accompanying Form PTO-1449. A copy of the document is also submitted herewith. The Examiner is requested to make this document of record.

This Information Disclosure Statement is submitted pursuant to 37 CFR §1.97(b) as it within three months of the filing date of a national application other than a continued prosecution application and/or before the mailing of a first Office Action on the merits. Accordingly, no fee is required.

Applicants would appreciate the Examiner initialing and returning the Form PTO-1449, indicating that the information has been considered and made of record herein.

The information contained in this Information Disclosure Statement under 37 C.F.R. §1.555 is to the best of my knowledge and is not to be construed as a representation that: (i) a complete search has been made; (ii) additional information material to the

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2350 Mission College Blvd. Suite 360 Santa Clara, CA 95054 (408) 982-8200 FAX (408) 982-8210 examination of this application does not exist; (iii) the information, protocols, results and the like reported by third parties are accurate or enabling; or (iv) the above information constitutes prior art to the subject invention.

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Michael J. Halbert

Respectfully submitted,

Michael J. Halbert Attorney for Applicants Reg. No. 40,633

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U.S. Department of Commerce, Patent and Trademark Office				Application No.: 10/634,568								
					Filing Date:			August 8, 2003				
(Use several sheets if necessary)					First Named Inventor:			Jaime Poris				
					Group Art Unit:			Unknown				
					Examiner Name:			Unkonwn				
					Confirmation No.:			Unkonwn				
					Attorney Docket No.: NAN042-1D US							
TADEM	ARX		U.S. P	atent Documents	S							
*Examiner Initial		Document Number	Date	Name		Class	Subclass		Filing Date If Appropriate			
	26.	6,568,290	May 27, 2003	Poris		73	866			4		
	27.	2002/0174714A1	Nov. 28, 2002	McWaid et al.		73	105					
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	31.	Malacara, Daniel et a	1. "Interferogram A	Analysis For Opt	ical Testi	ng" 1998,	Marc	cel Dekker	, Inc. pp. 113	}		
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Examiner			Date Considered	Date Considered								
*EXAMINER: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.												